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| Sheet |  | of |  | Compl te if Known      |                      |
|-------|--|----|--|------------------------|----------------------|
| 1     |  | 1  |  | Application Number     | 10/613,700           |
|       |  |    |  | Filing Date            | July 3, 2003         |
|       |  |    |  | First Named Inventor   | Khursheed, Anjam     |
|       |  |    |  | Art Unit               | 2872                 |
|       |  |    |  | Examiner Name          | Not assigned yet     |
|       |  |    |  | Attorney Docket Number | NAA 0016 PA/41049.18 |

**NON PATENT LITERATURE DOCUMENTS**

| Examiner Initials* | Cite No. <sup>1</sup> | Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published. | T <sup>2</sup> |
|--------------------|-----------------------|---|----------------|
| JB                 |                       | J. STOHR & S. SANDERS, "X-ray spectro-microscopy of complex materials and surfaces", IBM J. Res Develop, (2000), vol. 44, p. 535-551.   |                |
| JB                 |                       | Omicron Vakuumphysik GMBH, "Focus PEEM", January 2001, Germany  |                |
| JB                 |                       | D. PREIKSZAS et al., "SMART electron optics", 12th European Congress on Electron Microscopy, Proceedings Volume III, Instrumentation and Methodology, (2000), p. 18-84.   |                |
| JB                 |                       | H. SPIECKER et al., "Time-of-Flight Photoelectron Emission Microscopy TOF-PEEM: first results", Nucl. Instrum. and Methods in Phys. Res., (1998), A 406, p. 499-506.  |                |
| JB                 |                       | G.K.L. MARX et al., "Multipole WIEN-filter for a high-resolution X-PEEM", Journal of Electron Spectroscopy and Related Phenomena, (1997), Vol. 84, p. 251-61.   |                |
| JB                 |                       | A. KHURSHEED, "Ultimate resolution limits for scanning electron microscope immersion objective lenses," Optik, (2002), vol. 113, no. 2, p. 67-77.   |                |
| JB                 |                       | B.P. TONNER et al., "A Photoemission microscope with a hemispherical capacitor energy filter", Journal of Electron Spectroscopy & Related Phenomena, (1997), vol. 84, p. 211-29   |                |
| JB                 |                       | J.E. Barth & P. Kruit, "Addition of different contributions to the charged particle probe size", Optik, (1996), vol. 101, no. 3, p. 101-109.  |                |
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|--------------------|--------------------|-----------------|---------|
| Examiner Signature | <i>Jack Berman</i> | Date Considered | 6/28/04 |
|--------------------|--------------------|-----------------|---------|

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